

Another Patent on the Wall of Fame

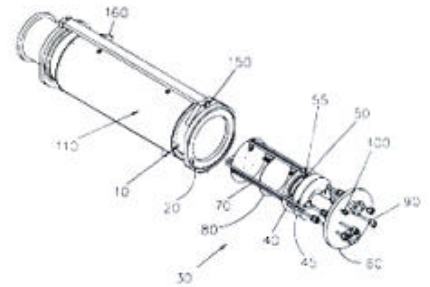


On Monday, May 2, 2005, two patent attorneys from the law firm of Fredrikson & Byron presented Hans Melgaard, and Despatch Industries, with a patent plaque for U.S. Patent No.: US6,879,779 B2. Hans has over thirty domestic and international patents to his name.

Hans Melgaard noted that this invention allowed Despatch to shorten the cycle time for uniform heat up and cool down in a vacuum furnace. It helped to achieve a higher number of semiconductor wafers processed per hour. This invention can be used on diffusion furnaces, magnetic annealing tools, and polyimide cure tools. The first product using this patented invention has now been in operation for a year and a half.

Pictured l-r are Adonis Neblett and Frank Piskolich presenting the Despatch patent plaque to Hans Melgaard and Patrick Peyton.

ABSTRACT: A vacuum oven with heat transfer fluid conduits. The oven of the invention generally includes a shell into which a removable rack may be placed. The rack has at least one plate which may be heated or cooled by a plate fluid conduit in contact with the plate and through which a heating or cooling fluid may be passed. Work pieces may be loaded on the rack, the rack placed in the shell, the shell sealed, and a vacuum drawn within the shell. The work pieces loaded on the rack are primarily heated and cooled by conductive and radiant heat transfer because of the limited amount of thermally conductive gases within the shell.



This article originally appeared in our client's (Despatch Industries) internal newsletter and is reprinted with permission. Fredrikson & Byron attorneys Adonis Neblett and Frank Piskolich drafted and prosecuted the patent.